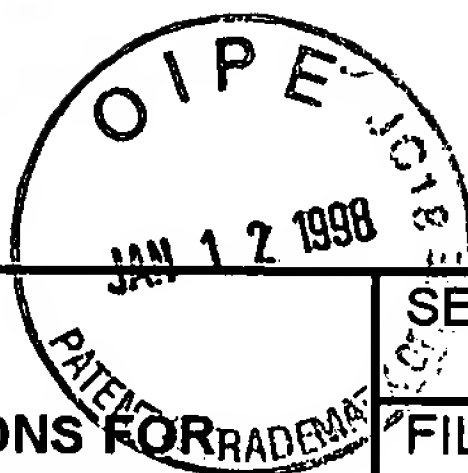


FORM PTO-1449

**LIST OF PATENTS AND PUBLICATIONS FOR
APPLICANT'S INFORMATION DISCLOSURE
STATEMENT**

(use several sheets if necessary)



SERIAL NO.

08/853,323

CASE NO.

7103/30

FILING DATE

May 8, 1997

GROUP ART UNIT

3203

APPLICANT(S): Homayoun Talieh et al.

#4
1/20/98
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REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS/ SUBCLASS	FILING DATE
GN	A1	619,399	02/1899	Fischer	—	—
	A2	3,447,306	06/1969	Jakimcius	—	—
	A3	3,654,739	04/1972	Stoy et al.	—	—
	A4	3,753,269	08/1973	Budman	—	—
	A5	3,906,678	09/1975	Roth	—	—
	A6	4,016,857	04/1977	Hall	—	—
	A7	4,347,689	09/1982	Hammond	—	—
	A8	4,416,090	11/1983	Jonasson	—	—
	A9	4,593,495	06/1986	Kawakami et al.	—	—
	A10	4,628,640	12/1986	Johannsen	—	—
	A11	4,642,943	02/1987	Taylor, Jr.	—	—
	A12	4,704,823	11/1987	Steinback	—	—
	A13	4,811,522	03/1989	Gill, Jr.	—	—
	A14	4,934,102	06/1990	Leach et al.	—	—
	A15	4,941,293	07/1990	Ekhoff	—	—
	A16	5,081,795	01/1992	Tanaka et al.	—	—
	A17	5,205,082	04/1993	Shendon et al.	—	—
	A18	5,212,910	05/1993	Breivogel	—	—
	A19	5,230,184	07/1993	Bukhman	—	—
	A20	5,232,875	08/1993	Tuttle et al.	—	—
	A21	5,246,525	09/1993	Sato	—	—
	A22	5,274,964	01/1994	Simpson et al.	—	—
	A23	5,276,999	01/1994	Bando	—	—
	A24	5,287,663	02/1994	Pierce et al.	—	—
	A25	5,297,361	03/1994	Baldy et al.	—	—
	A26	5,329,732	07/1994	Karlsrud et al.	—	—
	A27	5,329,734	07/1994	Yu	—	—
	A28	5,335,453	08/1994	Baldy et al.	—	—
	A29	5,399,125	03/1995	Dozier	—	—
	A30	5,456,627	10/1995	Jackson et al.	—	—

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS/ SUBCLASS	TRANSLATION YES NO
GN	A31	EP 517 594	12/92	EPO	—	
GN	A32	EP 517 595	12/92	EPO	—	

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	APPLICANT(S): Homayoun Talieh et al.	

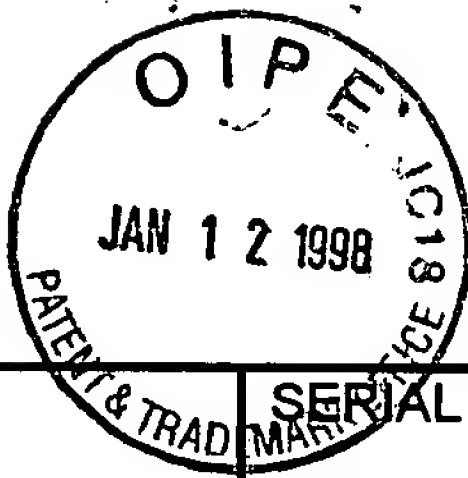
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	A36	63267155	11/88	Japan			
	A37	7111256	04/1975	Japan			
	A38	JP 59-232768	12/1984	Japan			
	A39	JP 63200965	08/1988	Japan			
	A40	JP 63251166	10/1988	Japan			
	A41	JP 4-250967	09/1992	Japan			
	A42	DE 3411 120 A1	03/1983	Germany			
	A43	PCT WO 94/17957	08/1994	PCT			
	A44	2007784	02/1994	Russia			

EXAMINER INITIAL	OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)	
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GN	A46	"Application of Chemical Mechanical Polishing to the Fabrication of VLSI Circuit Interconnections", William J. Patrick, William L. Guthrie, Charles L. Stadley and Paul M. Schiabe, J. Electrochem. Soc., Vol. 138, No. 6, June 1991, pp. 1778-1784
GN	A47	"Theory & Practice of Lubrication for Engineers", Dudley Fuller, Wiley-Interscience, 1st ed., pp. 22-25 and 86
GN	A48	Practical Ideas, June 1994, page 67

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